

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	249	((134/198,199,200,902.ccls. or 216/2, 92.ccls.) or 156/345.21,345.51,345.54, 345.55.ccls.) and @pd>"20060512"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/12/06 10:12
L2	5	((yuji near2 kamikawa).in. or (koji near2 egashira).in.) and @pd>"20060512"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/12/06 10:21
L3	3909	((nozzle or spray\$3) with (fan or plane or planar)) and (semiconductor or wafer or substrate).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/12/06 10:22
L4	687	((((nozzle or spray\$3) with (fan or plane or planar)) and (semiconductor or wafer or substrate))).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/12/06 10:23
L6	16	((((nozzle or spray\$3) with (fan or plane or planar)) and (semiconductor or wafer or substrate) and horizontal\$2 with (axis axes))).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/12/06 10:23
L7	425	((semiconductor or wafer or substrate)) and ((wash\$3 or rins\$3 or process\$3 or clean\$3 or etch\$3) with (liquid or fluid)) and (chamber or container or vessel or tank) and (hold\$3 or chuck\$3 or rotor or secur\$3 or support\$3) and ((nozzle or orifice or spray\$3) with (fan or plane or planar))).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/12/06 10:27